

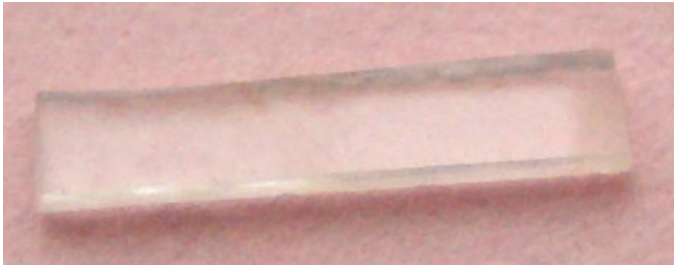
GaN component technology development in Europe - current status and perspectives

A Barnes TEC-QTC

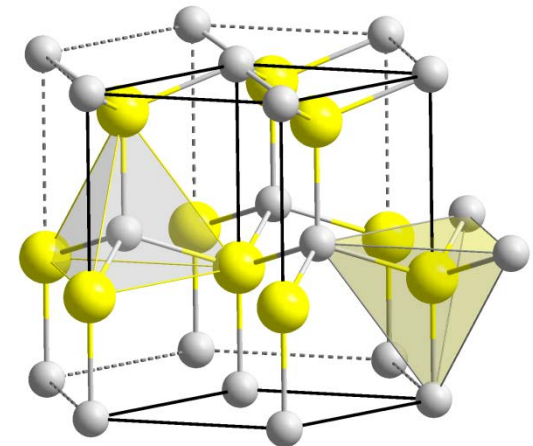


esccon 2013
12 - 14 march 2013

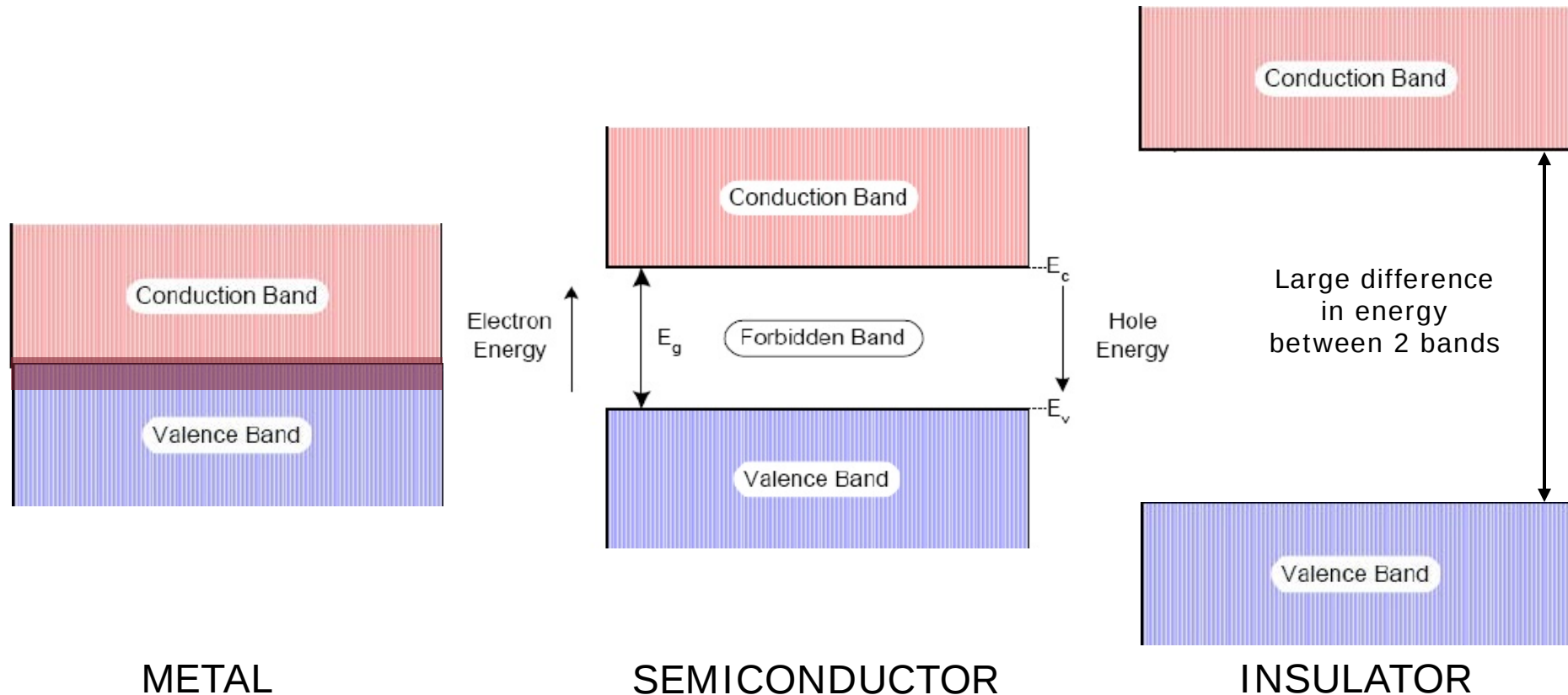
- Introduction to WBG semiconductors
- ESA IPC roadmap and strategy 2006-2012
- Key achievements from ongoing projects
- Conclusions
- Issues and next steps



1. Introduction to WBG semiconductors

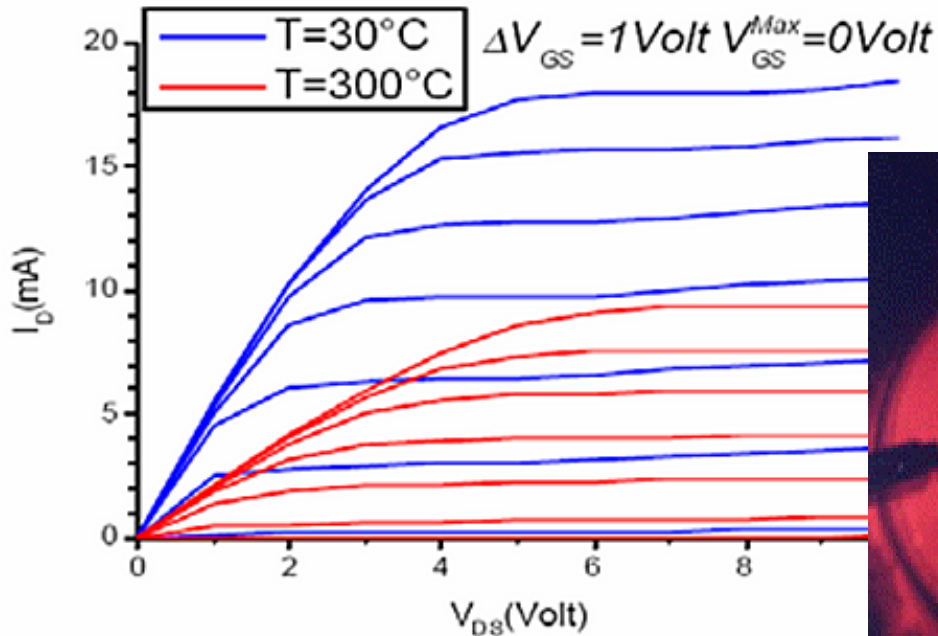


What is a wide band gap semiconductor?

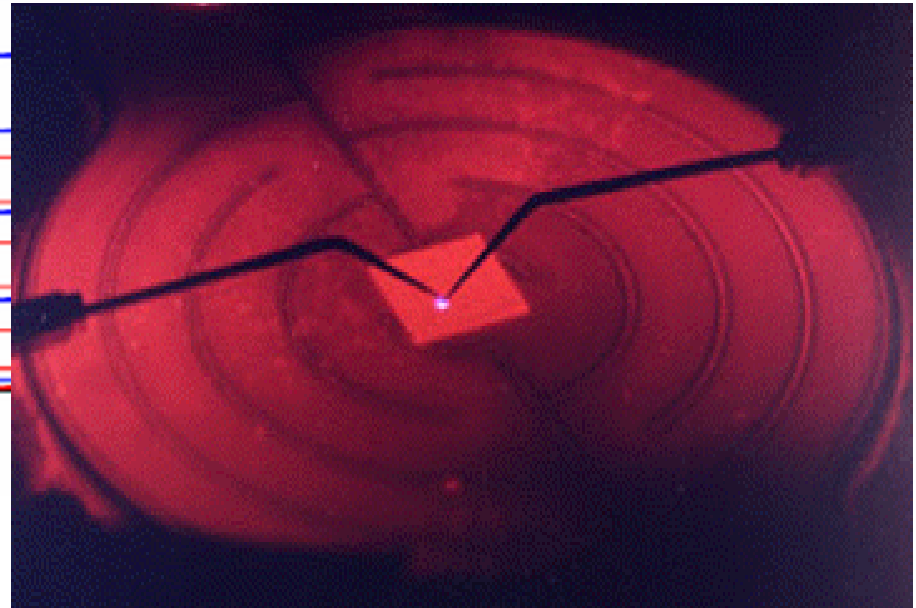


Properties of WBG semiconductors

	Narrow band gap $E_g < 1\text{eV}$		Intermediate band gap $E_g \approx 1\text{eV}$			Wide band gap $E_g > 3\text{eV}$	
	InSb	InAs	$\text{In}_{0.53}\text{Ga}_{0.47}\text{As}$	Si	GaAs	SiC	GaN
Electron Mobility $\times 10^3 (\text{cm}^2\text{V}^{-1}\text{s}^{-1})$	30	16	8	0.6	4.5	0.8	1.6
Electron Velocity (10^7 cm/s)	5.0 (peak)	4.0 (peak)	2.7 (peak)	1.0 (sat.)	2.0 (sat.)	2.0 (sat.)	2.7 (sat.)
Band-gap (eV)	0.18	0.36	0.72	1.1	1.43	3.2	3.4
Breakdown field (MV/cm)	0.01	0.1	0.4	0.6	0.6	3.5	3.5
Thermal conductivity (W/cmK)	0.18	0.27	≈ 0.3	1.5	0.46	3.55	1.7
Heterojunctions	Yes	Yes	Yes	Yes	Yes	No	Yes



GaN HEMT DC IV characteristic
 $T_{amb}=30^\circ\text{C}$
 $T_{amb}=300^\circ\text{C}$



Photodiode (25mm²) operating at 600°C

- High temperature operation
- Inherent radiation hardness

Why the interest in SiC and GaN?

Material properties



- High electron saturation velocity $\approx 2.5 \times 10^7$ cm/s
- High carrier density $\approx 10^{13}$ /cm²
- Large bandgap
 - High breakdown field
 - High temperature operation
 - Radiation robustness
- Heterostructure design (GaN)

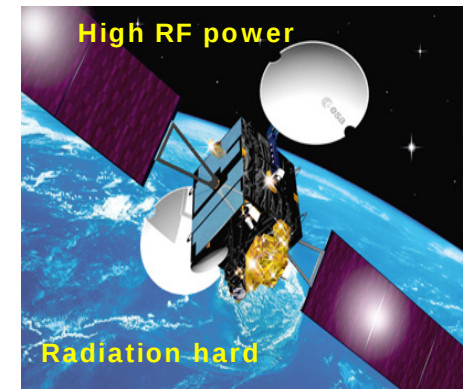
Device performance



- High output power density, small size, easy impedance match
- High voltage operation, simplified voltage conversion
- Operation under extreme environmental conditions

Applications

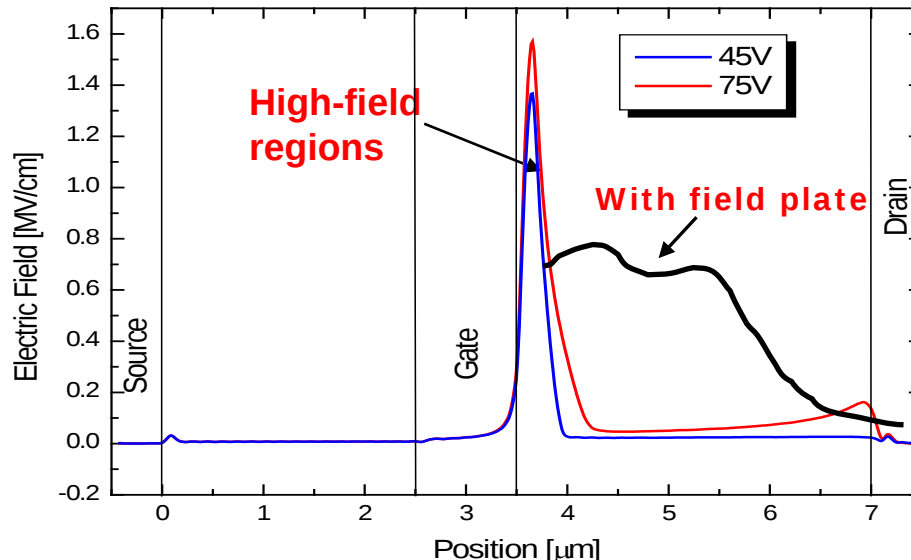
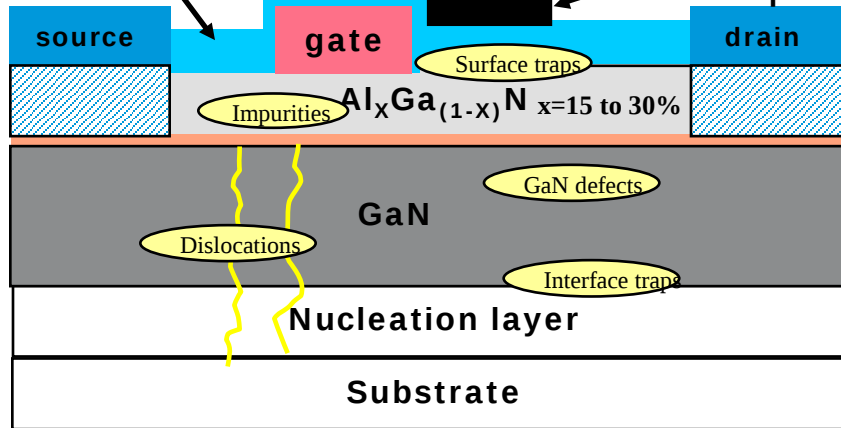
- Telecommunications
- Radars
- Novel sensors, detectors
- Power switching
- Solar cells, blocking diodes



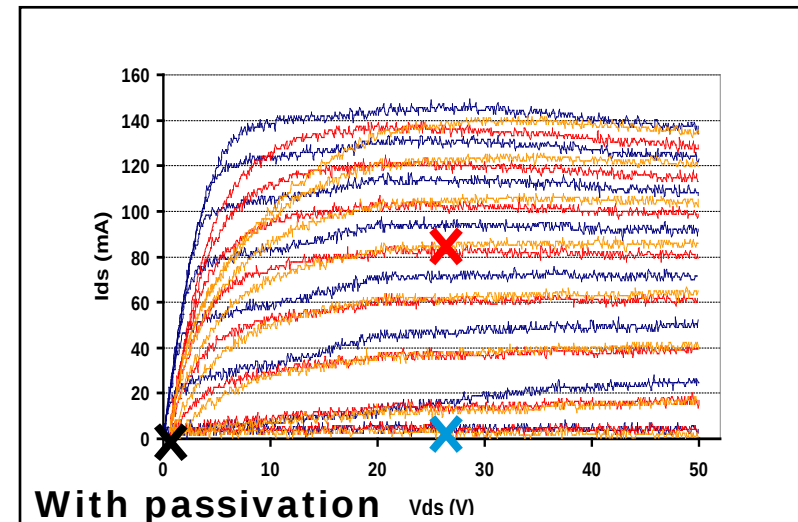
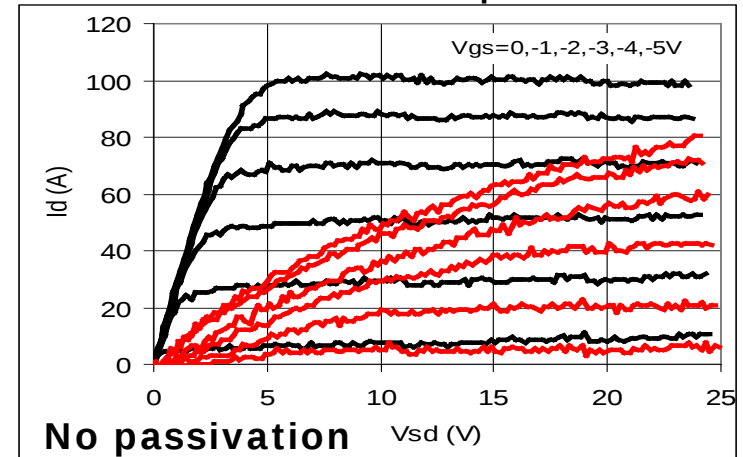
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AlGaN / GaN HEMT performance issues

SiN passivation field plate



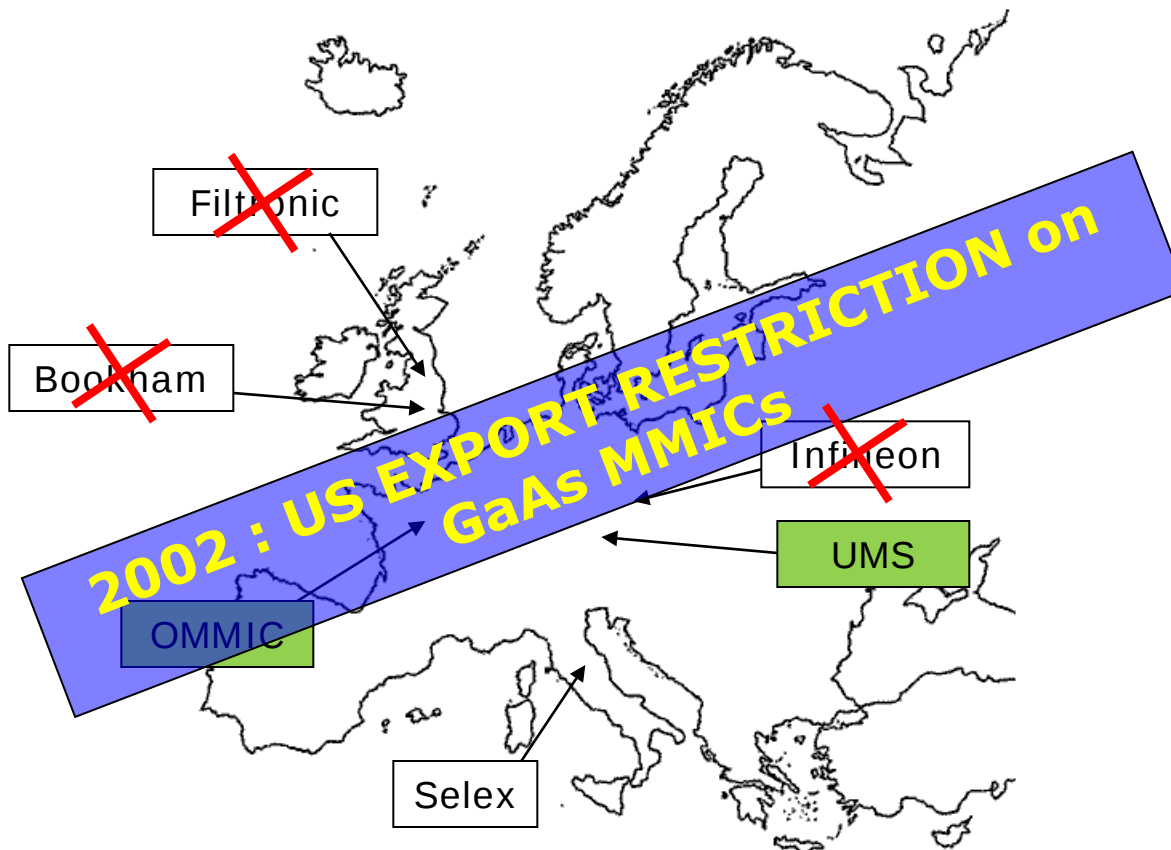
Surface state dispersion



2. ESA IPC roadmap and strategy 2006-2012



European GaAs microwave foundry situation 2002

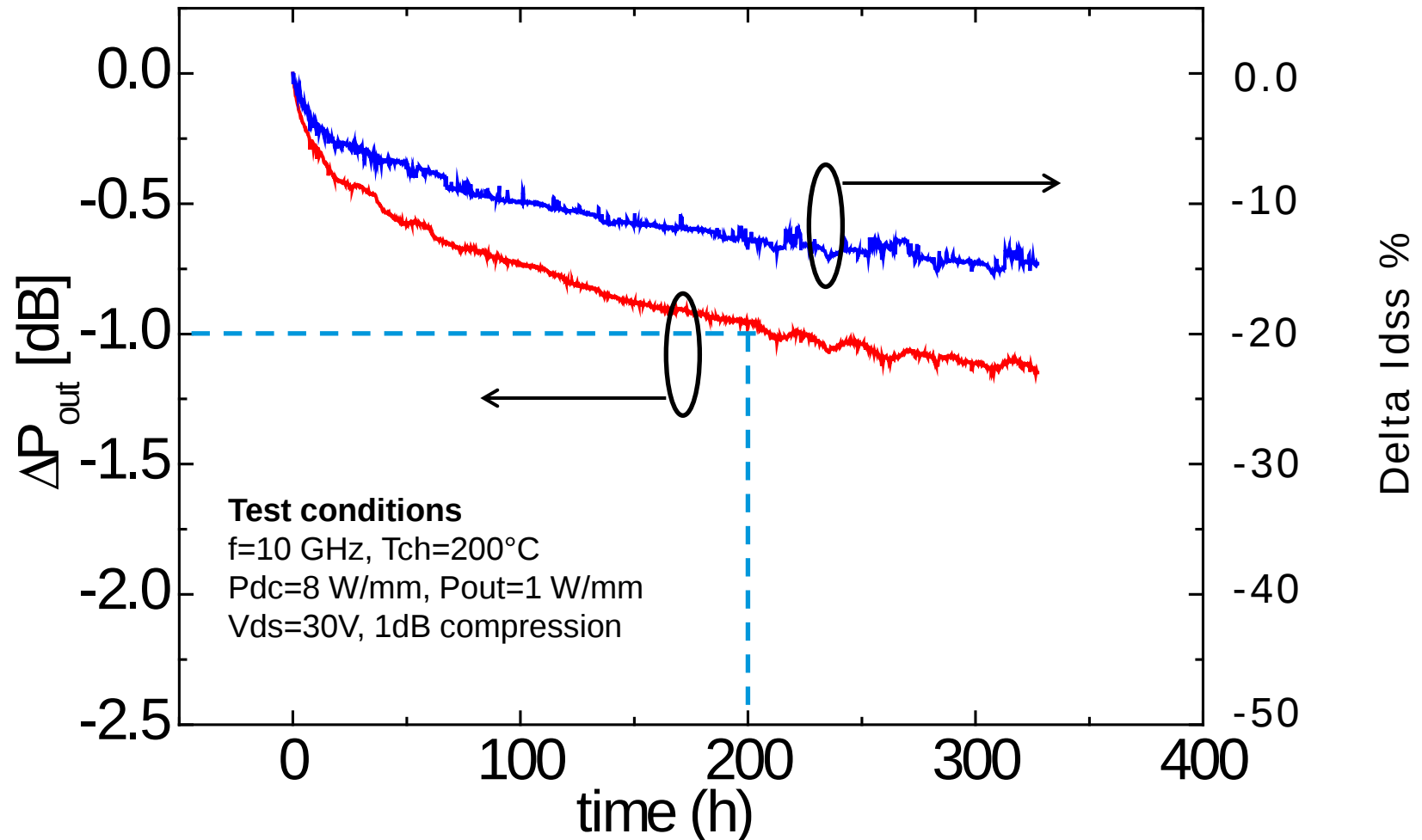


- 6 potential foundry sources



- 2 primary merchant foundry sources + Selex
- Many companies using Triquint products

- Rapid RF output power degradation after 10-200 hundred hours operation



- Safeguard European access to strategic microwave components (GaN)
- Secure European non-dependence

1. Improving GaN device reliability for space
2. Establishment of an independent European supply chain that is accessible by space industry
3. Improved understanding of the disruptive benefits offered by GaN
4. Developing appropriate thermal management + packaging techniques
5. Investigation of non-RF component applications

ESA INITIAL R+D EMPHASIS

(1) OPTOELECTRONICS

LEDs
Lasers
UV detectors
Solar cells

LARGE ESTABLISHED MARKET
(€6bn by 2009)

(2) MICROWAVE ELECTRONICS

Low noise, high frequency

High Power (>10 Watts)

Mobile Communications
Radar Systems
Satellite Communications
Magnetron replacement

SMALL - MEDIUM MARKET (€0.3bn by 2009)

STRONG AEROSPACE INTEREST

DIFFERENT MATERIALS REQUIREMENT TO OPTOELECTRONICS

(3) HIGH POWER + HIGH VOLTAGE ELECTRONICS

DC-DC power conversion
power switches / rectifiers

LARGE MARKET (>€3bn by 2010))
IMMATURE FIELD

Leverage materials and reliability know-how “investment” towards Power Conversion and Photonics markets

Demonstrate - space “spin-in”

Activities initiated



- 1. Improving GaN device reliability for space
 - GREAT² (GSTP)
 - GaN HEMT reliability Physics (NPI)

- 2. Establishment of an independent European supply chain, accessible by space industry
 - EuSiC (FP7)
 - Low dislocation density GaN substrates (PECS)
 - Establishment of commercial GaN epitaxy supplier (GSTP)

- 3. Improved understanding of the disruptive benefits offered by GaN
 - Numerous TRP activities
(e.g. Single chip HPA/LNA for radar applications, GaN power stage based on European technology for Navigation SSPA...)

- 4. Developing appropriate thermal management + packaging techniques
 - AGAPAC (FP7)

- 5. Development of non-RF component applications
 - GaN device manufacture compatible with a Si production environment (GSTP)

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3. Key achievements and highlights



GaN Reliability Enhancement and Technology Transfer Initiative (GREAT²)



- Establishment of space compatible European GaN HEMT / MMIC foundry process
 - 0.5μm gate length GaN HEMT process
 - (UMS GH50, useable to 6GHz)
 - 0.25μm gate length GaN MMIC process
 - (IAF GaN25, UMS GH25, useable to 20GHz)
- GREAT² consortium
 - Leading European research institutes and manufacturing industry
 - Technology transfer
 - Planned processing throughput ≈ 170 wafers
 - Space operation potential validated
 - RF lifetime, radiation, ESD, H₂, vibration, shock
 - Independent validation at ESA
- Ready for ESA space evaluation 2014



GREAT² – example L-Band milestone targets



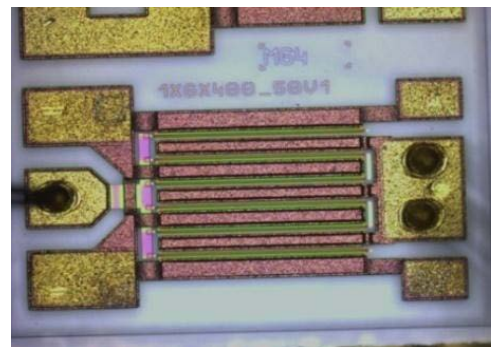
	Milestone M3	Milestone M5	Milestone M7	
Operating frequency (GHz)	1.7	1.7	1.7	*Power density ≥ 5 W/mm Performance
Gate width (mm)	1.6	2.4	2.4	
Drain Bias (V)	$\geq 50V$	$\geq 50V$	$\geq 50V$	
*Output power P_{out} at max. PAE	≥ 37	≥ 37	≥ 37	
PAE %	≥ 40	≥ 55	≥ 55	
Associated gain at P_{out}	≥ 15	≥ 15	≥ 15	
MTTF for $\Delta P_{xdB} \leq 1dB$, $T_j \geq 230^\circ C$	$\geq 1 \times 10^3$ h	$\geq 1 \times 10^4$ h	$\geq 1 \times 10^6$ h	Reliability
Pout variation (dB)	± 1.5	± 1	± 0.5	Yield
RF small signal gain uniformity (dB)	1.5	1	1	
Wafer yield (%)	≥ 50	≥ 60	≥ 70	
Radiation sensitivity (TID, displacement, SEE)	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	Space Environment
Hydrogen poisoning	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	$\leq 15\%$ drift (I_{dss} , V_t , g_m)	

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Milestone M5 : Technology evaluation vehicles

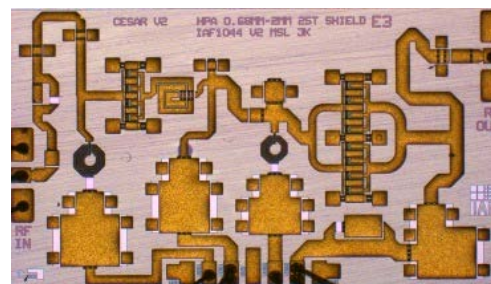


- L-band discrete transistor (1.7GHz)
 - $V_{ds}=50V$, $P_{out} \geq 40dBm$
 - $PAE > 65\%$
 - Internal matching, 1.7GHz
- X-band MMIC (8.5GHz)
 - $V_{ds}=30V$, $P_{out} = 38-40dBm$
 - $PAE = 40\%$
- Over 130 hermetic packaged parts at each milestone
 - 60 parts independently tested by ESA
 - DC and RF validation over stress temperature range



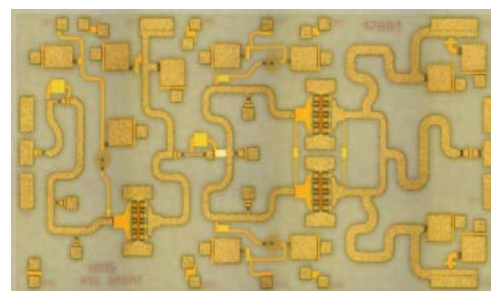
L-band

UMS GH50_10



X-band

IAF GAN25



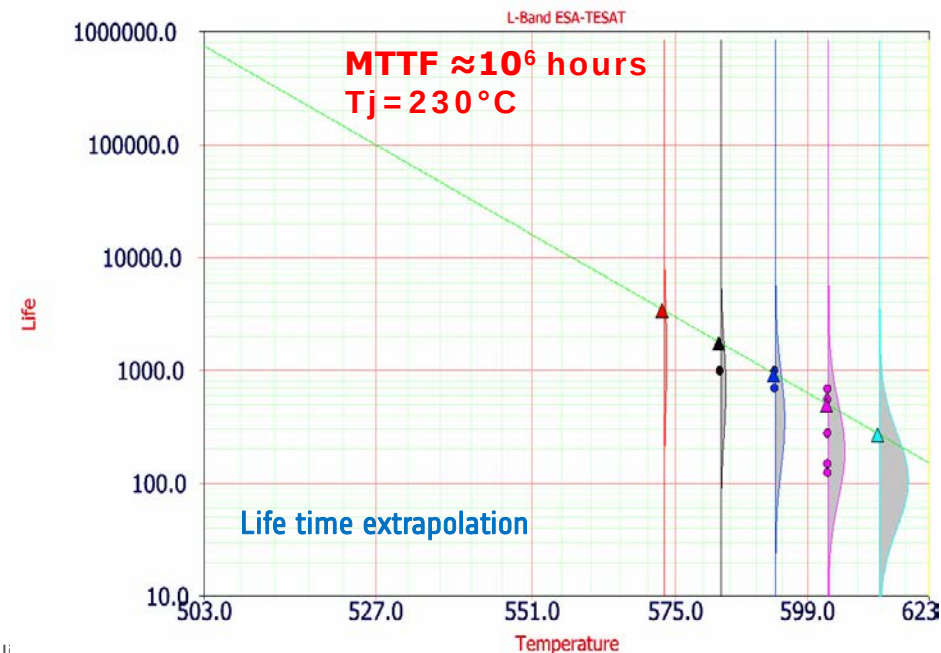
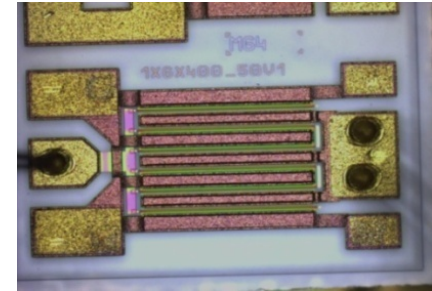
UMS GH25_10

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GREAT² L-band RF life test results



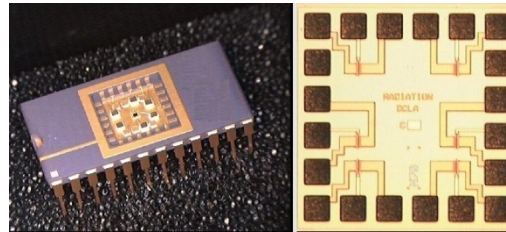
- 3000 h accelerated RF life test
 - UMS GH50 L-band 6 x 400 μm power cell
 - 1.7 GHz CW RF operation at 50 V
 - 310 °C to 390 °C peak channel temperature
 - $P_{\text{out}} > 10$ W (initial), > 4 dB compression (at stress conditions)
- Life time extrapolation to 230 °C peak channel temperature
 - Failure limit:
1 dB output power degradation
 - Activation energy 2.0 eV
 - $\text{MTF} > 1 \times 10^6$ h
(lower limit for C.L. 60%)
- Final 4000h RF life test
ongoing as part of M7 campaign



GREAT² Proton and gamma irradiation

■ Proton irradiation

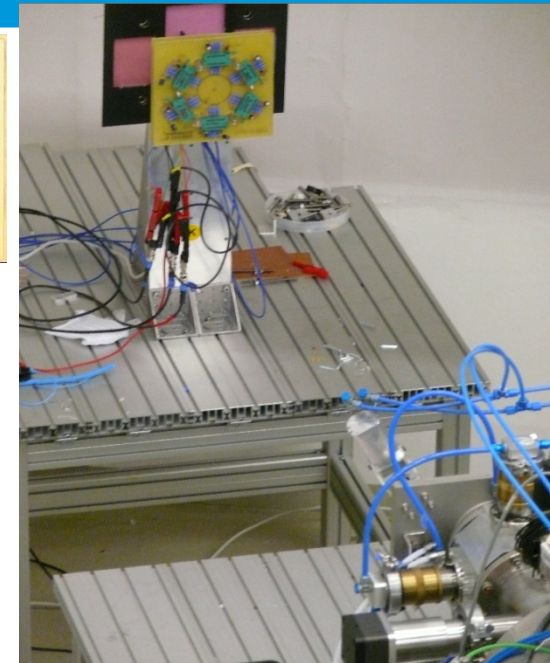
- Proton energy 35 MeV
- Flux $\sim 2 \times 10^9 \text{ p cm}^{-2} \text{ s}^{-1}$
- Fluence $> 2 \times 10^{12} \text{ p cm}^{-2}$



Radiation test PCM

■ ⁶⁰Co Gamma irradiation

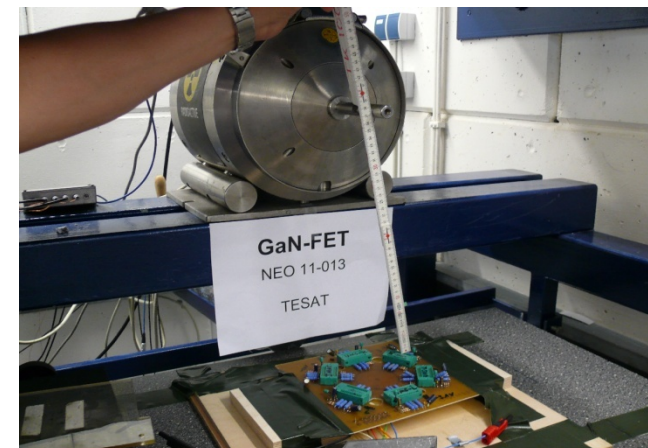
- Dose rate 3.6 kRad/h
- Up to 1 MRad (10 Gy)



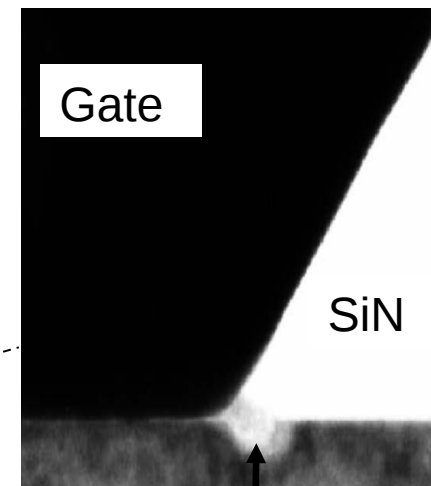
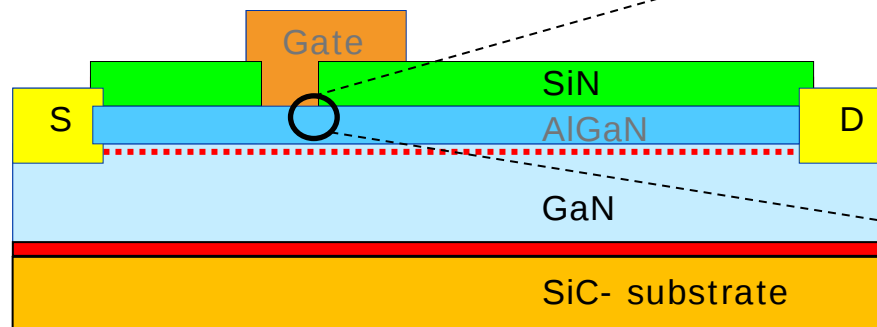
■ Key parameter drift of radiation PCMs

- UMS GH50 and GH25
- I_{dss} , V_{th} and $g_m < 10 \%$

■ Heavy ion tests no SEB up to $V_{ds}=125V$



- High peak temperature at the Schottky gate
 - Wide bandgap semiconductor is OK
 - But metals may be prone to **diffusion and interlayer effects**
- Passivation and epi layer defects
 - **Trapping effects** causing slow variations over time
- High field strength at drain-side gate edge
 - **Pitting** (chemical reaction) occurring
 - **Charge and interface stress** voltage and temperature dependent



Pitting after 3000 h RF life test @ $T_{ch} > 300\text{ }^{\circ}\text{C}$



Agency

European preferred parts list



- UMS GH50_10 GaN process accepted for EPPL 2 listing November 2012
 - 2 years earlier than planned
- Space de-rated peak channel temperature $\leq 160^{\circ}\text{C}$
 - Limited to a 40W part for first release
- Additional work required to improve reliability of GH25 process
 - MIM capacitor robustness
 - Improved gate module
- Full, more extensive, space evaluation planned for GH50_20 (2013) and GH25_10 process (2014)



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European Space Components Coordination



EPPL | *European Preferred Parts List*

united
monolithic
semiconductors



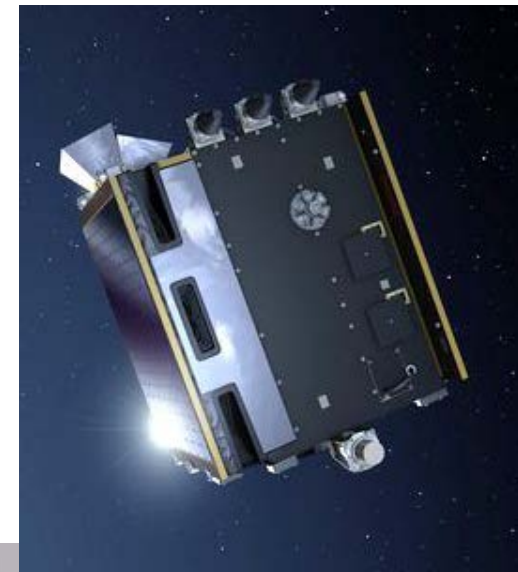
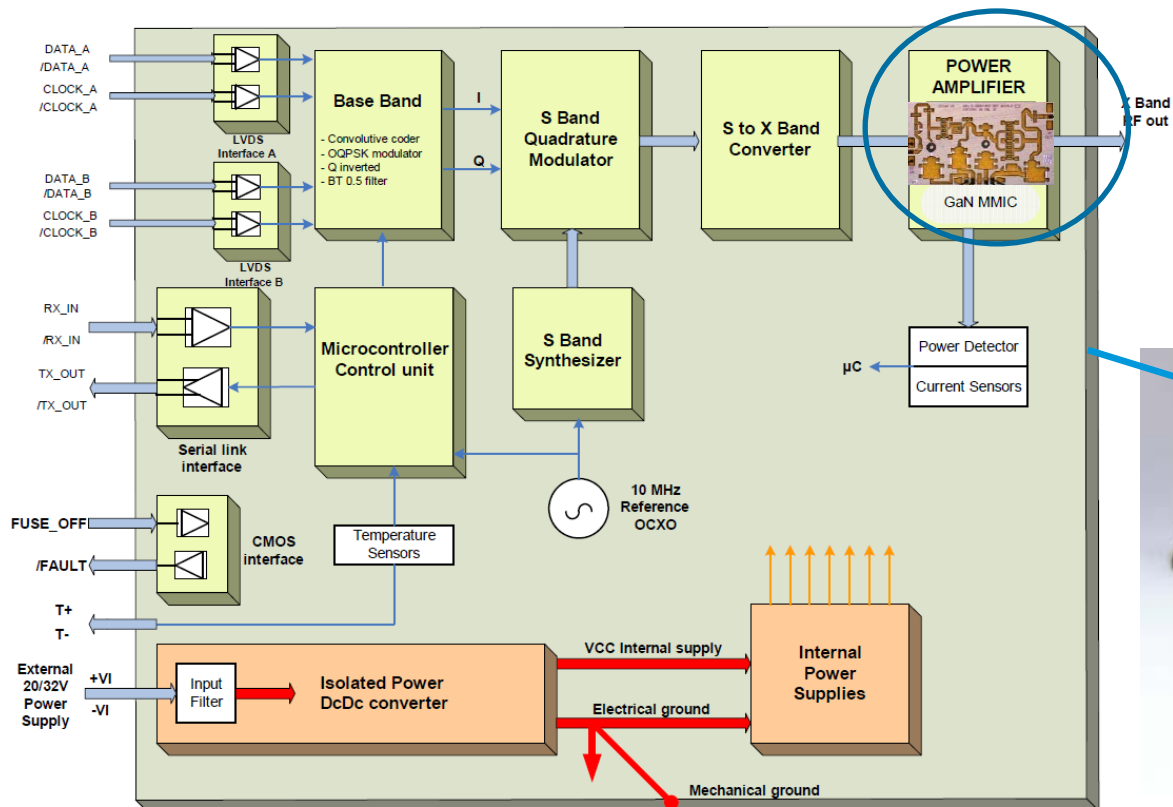
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Early in orbit demonstration

- PROBA V 3rd telemetry transmitter using GaN X-band MMICs from GREAT² project

- OQPSK modulation, 10 to 100Mbps bit rate
- >6W RF output power (power flexibility)

- First demonstration of European sourced GaN technology in space



Establishment of an independent European supply chain accessible by space industry



~~EUROPEAN~~ RF INDUSTRIAL GaN SUPPLY CHAIN OPTIONS PRE 2008



US

S.I. SiC substrates



US

GaN epitaxy



US



JP

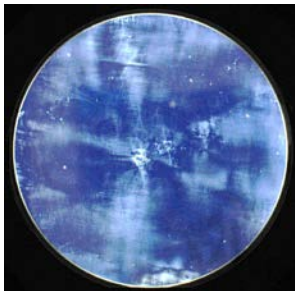
GaN foundry



JP

High thermal dissipation packages

EUROPEAN RF INDUSTRIAL GaN SUPPLY CHAIN OPTIONS >2012



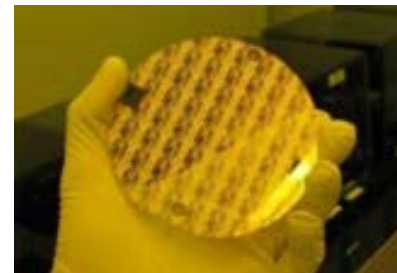
S.I. SiC substrates

EuSiC (FP7)



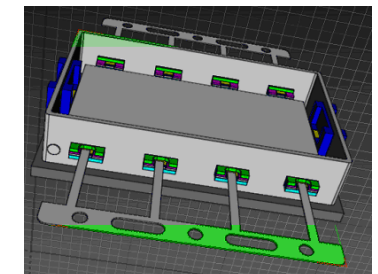
GaN epitaxy

ESA GSTP



GaN foundry

ESA TRP, GSTP, ECI



High thermal dissipation packages



(FP7)

GaN HEMT for high efficiency DC-DC converters

- Lower on state resistance
- Reduced Miller capacitance
- High frequency switching

Switching frequency ↑

L, C values ↓

62.5 kHz

- Two stage EMI filter needed
- Large inductors needed

750 kHz

- Only need single stage EMI filter
- Less inductance for differential noise filtering
- Saves one filter stage
- **And** provides lower loss



Left hand demo board
Source: Infineon

transphorm

30

US Dime

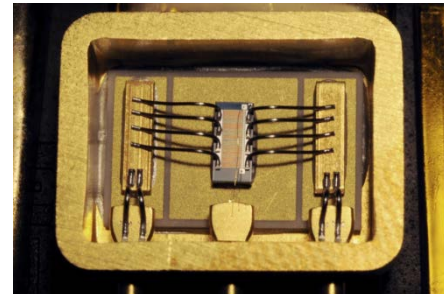
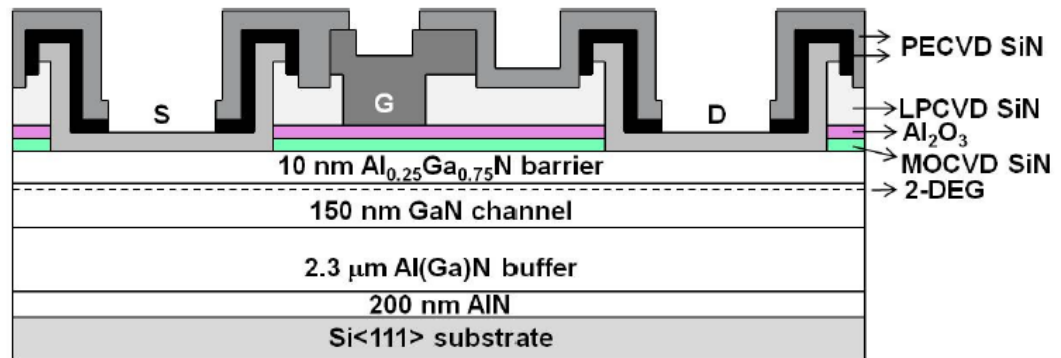
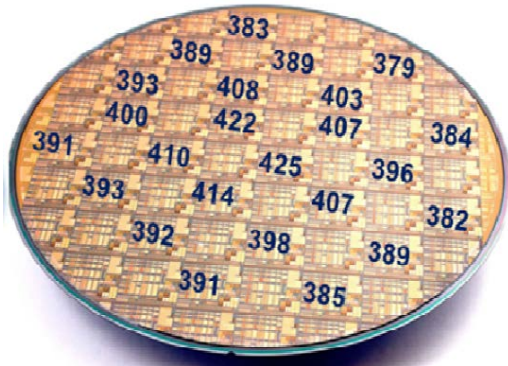
Boost DC-DC converter
GaN solution vs Si MOS

- 50% reduction in mass and volume
- 2-3% better efficiency

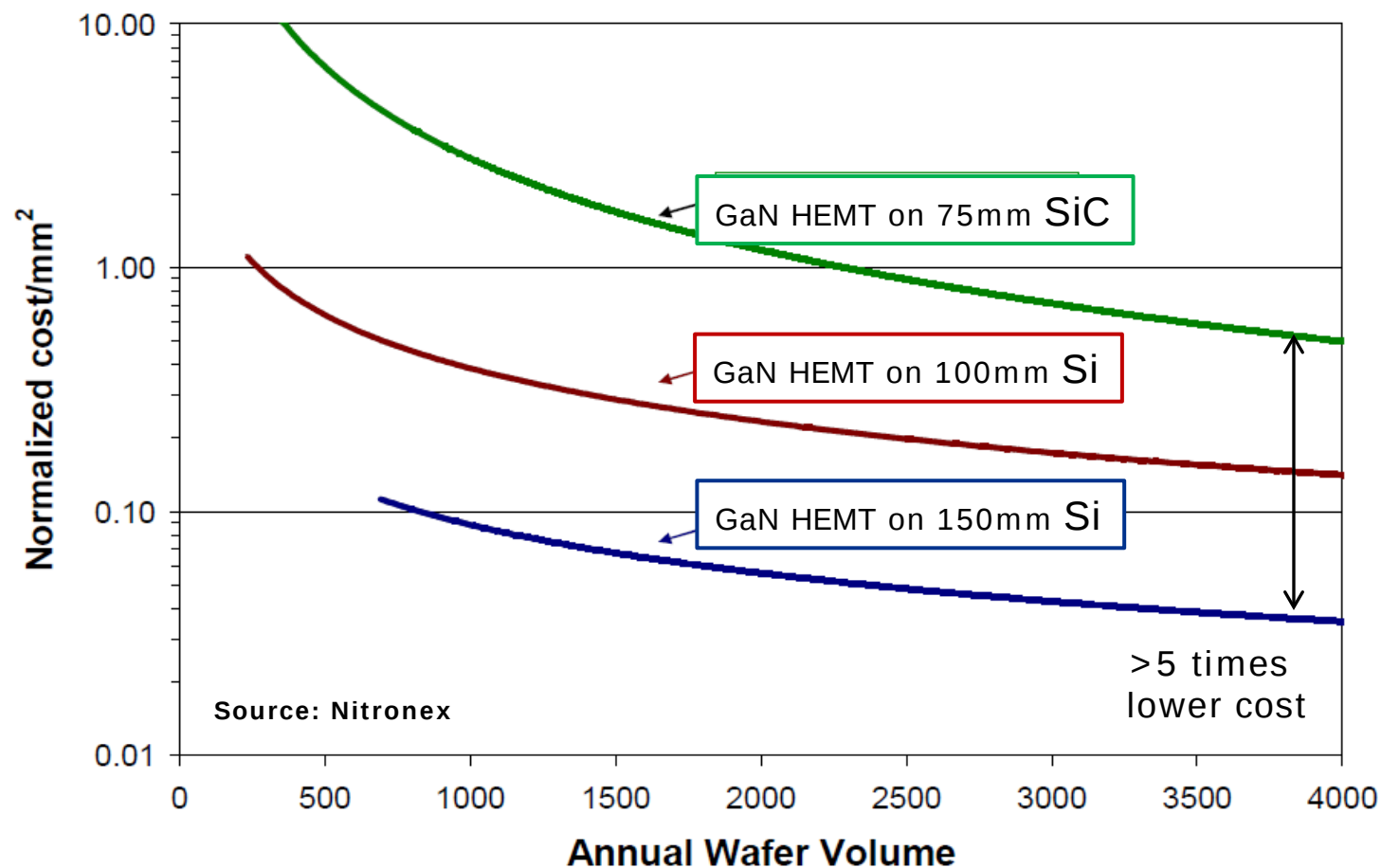
Development of wide band gap processing techniques compatible with a Si production environment “GaN in the line”



- ESA funded project to develop GaN on silicon power transistors using a Si CMOS compatible processing line
 - Fabrication on 150mm diameter silicon wafers for low cost
 - Novel Au free process, bi-layer insulated gate dielectric
 - Electrical performance and SEE radiation assessment

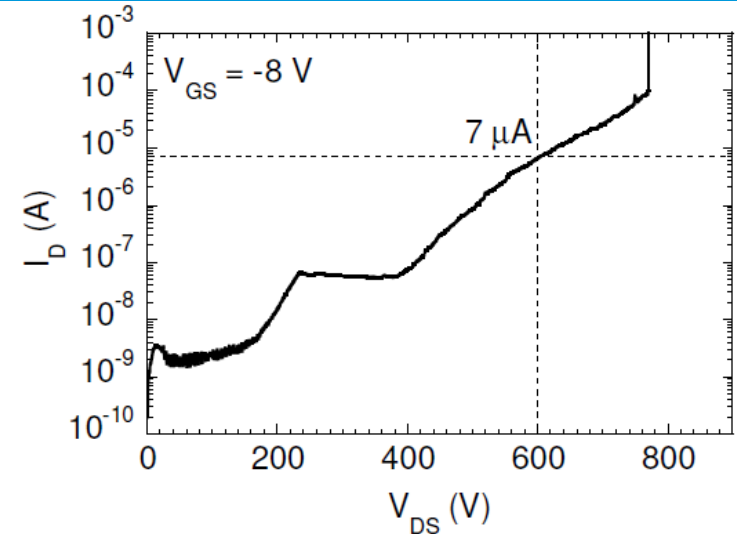
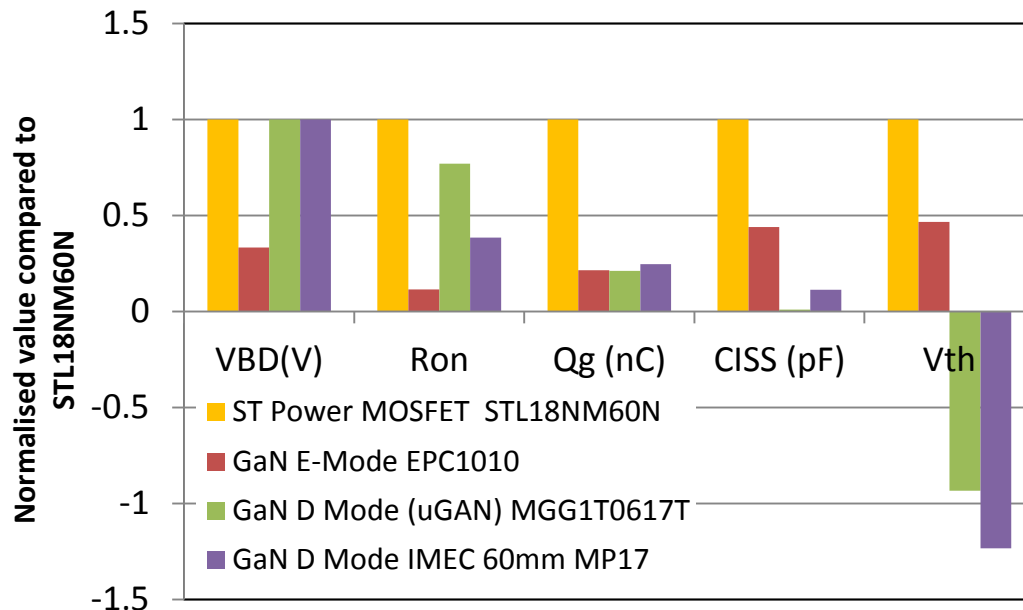


Why manufacture GaN on silicon?



“GaN in the line” key results

- Pilot manufacture through MiPlaza facility in Eindhoven (ex Philips line)
- Various transistor sizes
 - 10mm-100mm gate periphery
- Excellent yield, low leakage current
 - 7μA at 600V for 20mm (8A) device
 - Low capacitance



- State of art performance achieved in Europe
- **BUT** first devices are depletion mode
- Follow on GSTP6 program planned
 - Enhancement mode
 - Industrialisation
 - Space assessment

4. Conclusions

Summary of achievements



1. Major improvements made in terms of reliability
 - a. Operating lifetimes from a few hundred hours to over 1 million hours
2. Major advances in establishment of European supply chain
 - a. UMS GH50_10 process EPPL listed (2 years ahead of original planning)
 - b. Commercial SiC substrate and epitaxy suppliers established
3. Demonstration of AgD metal matrix packages (FP7 AGAPAC) for improved thermal management
 - a. 182W SSPA demonstration with 30% reduction in T_j compared to using conventional CuW baseplate material
4. First in-orbit demonstration of GaN X-band MMIC on PROBA V
5. Good progress on GaN on Si processing techniques made
6. The gap with ROW has closed from ≈ 10 years to around 4 years

- Validate, stabilise and space evaluate 1st generation GaN microwave processes
 - Promote GaN technology insertion for use in future ESA missions
- Develop appropriate ESCC standards for GaN microwave components
- Development of 2nd and 3rd generation GaN HEMT processes
 - Improved efficiency transistors
 - Larger diameter SiC substrates ($\geq 100\text{mm}$)
 - Higher frequency operation (Ka, Q, V, W-band)
 - Lower loss, robust on-chip passive components
- Improved thermal management and higher T_j operation
 - Semiconductor level (60-70% of ΔT drop)
 - Device processing techniques, epitaxy and substrate optimisation
 - Package level
 - Secure European supply capability of AgD metal matrix composites for use as package baseplates
 - Qualify packaged transistor power bars
- Development of European supply chain for power switching components
 - Develop GaN HEMT enhancement mode transistors, diodes, and transfer know-how from research institutes to manufacturing industry
 - Develop CMOS compatible processes on 150mm, 200mm and 300mm silicon substrates for low cost
 - Optimise GaN epitaxy for power switching performance (125V, 600V, 1000V operation)
 - Assess performance benefits, reliability and suitability for operation in space, perform space evaluation

**THANK YOU FOR
YOUR ATTENTION**